

***IN THE UNITED STATES PATENT AND TRADEMARK OFFICE***

Applicants: Shinichiro KOTAKE, et al.

Title: FLUE GAS TREATING SYSTEM AND PROCESS

Appl. No.: 09/658,928

Filing Date: September 11, 2000

Examiner: Timothy C. Vanoy

Art Unit: 1754

#71/B
7/15/03
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AMENDMENT AND RESPONSE UNDER 37 C.F.R. §1.111

Commissioner for Patents
P.O. Box 1450
Alexandria, Virginia 22313-1450

Sir:

This is a response to the Office Action mailed on March 11, 2003, in connection with the captioned application.

The amendments presented below comply with the revised amendment format permitted by the Notice from the Office of Patent Legal Administration of the U.S. Patent and Trademark Office dated February 10, 2003. Thus, the provisions of 37 C.F.R. § 1.121(a), (b), (c) and (d) are waived for amendments made to the claims, specification and drawings of this application.

Amendments to the Claims are reflected in the listing of claims beginning on page 2 of this document.

Remarks/Arguments begin on page 6 of this document.

Please amend the application as follows.